

PRE Amost A 5-1-00

In re application of:

Thomas A. Figura, Kevin G. Donohoe, & Thomas Dunbar

Serial No.:

Filed: December 22, 1999

Title: USE OF A PLASMA SOURCE TO FORM A LAYER DURING THE FORMATION OF A SEMICONDUCTOR DEVICE

Group Art Unit:

Application Examiner:

Atty. Docket: 94-0280.03

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Dear Sir:

DATE OF DEPOSIT 2-22-9

THEREBY CERTIFY THAT THIS PAPER IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE "EXPRESS MAIL POST OFFICE TO ADDRESSEE" SERVICE UNDER 37 C.F. R. § 1.10 ON THE DATE INDICATED ABOVE AND IS ADDRESSED TO THE ASSISTANT COMMISSIONER FOR PATENTS, WASHINGTOM, D.C. 2023.

Signature

Signature

After awarding this application the benefit of the filing date of the greatgrandparent application, filed June 2, 1995, please amend the accompanying continuation application as follows:

IN THE SPECIFICATION

After the title, please include the following --

RELATED APPLICATIONS

This application is a divisional of a pending U.S. application, serial number 09/046,835, filed on October 24, 1997; which is a continuation of U.S. application serial number 08/787,453, filed January 22, 1997 and issued on September 7, 1999 as U.S. Patent No. 5,950,092; which is a continuation of U.S. application Serial Number 08/458,861, filed June 2, 1995 and now abandoned. --